



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): MATSUI

Serial No.: 09/709,454

Filed: Nov. 13, 2000

Title: METHOD AND APPARATUS FOR
MECHANOCHEMICAL
POLISHING

Atty. Dkt.: 01-099

Group Art Unit: 3723

Examiner: SHAKERI, H.

*Cancelled
3-7-2003
H.C.*

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Assistant Commissioner for Patents
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Date: April 8, 2002

CERTIFICATE OF HAND DELIVERY

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Signature: *Kerry S Culpepper*

AMENDMENT

Sir:

In response to the Office Action mailed November 6, 2001, please enter the following amendments and consider the appended remarks.

IN THE CLAIMS

Please cancel claims 1 – 43 without prejudice.

Please add the following new claims:

44. (New) A method for mechanochemical polishing comprising:

preparing abrasive grains made of chromium (III) oxide; and

polishing a surface of a semiconductor wafer by mechanochemical polishing using the

abrasive grains; and

*Sub
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A1*